



Session Title:	[ThB1] Carbon Neutrality in Semiconductor Industry II
Session Date:	November 14 (Thu.), 2024
Session Time:	09:00-10:40
Session Room:	Room B (Grand Ballroom 1, 2F, Paradise Hotel Busan)
Session Chair:	Prof. Ayeon Kim (UNIST, Korea)

[ThB1-1] [Invited]

09:00-09:30

Cryogenic Plasma Etching for Semiconductor Processes Towards Carbon Neutrality

Shih-Nan Hsiao, Makoto Sekine (Nagoya Univ., Japan), Yoshihide Kihara, Ryutaro Suda (Tokyo Electron Miyagi Ltd., Japan), and Masaru Hori (Nagoya Univ., Japan)

[ThB1-2] [Invited]

09:30-10:00

Process Intensified Carbon Capture Solution for Semiconductor Industry: Rotating Packed-Bed

Manhee Byun, Boris Brigljević, SalaiSargunan S Paramanantham, Hyeonwoo Oh (Carbon Value, Korea), and Hankwon Lim (UNIST, Korea)

[ThB1-3]

10:00-10:20

Recent Efforts for Carbon Neutrality Study in Semiconductor Industry and Academia with Call for a Collaboration

Jong-Moon Park, Jin-Gi Hong, Bumsuk Jung, and Sang Jeon Hong (Myongji Univ., Korea)

[ThB1-4]

10:20-10:40

Economic and Environmental Analysis of Optimized Extractive Divided-Wall Distillation Process to Recover Semiconductor Industrial Waste

Aejin Lee, Yus Donald Chaniago, Jiwon Gu, Mingi Kim, and Hankwon Lim (UNIST, Korea)